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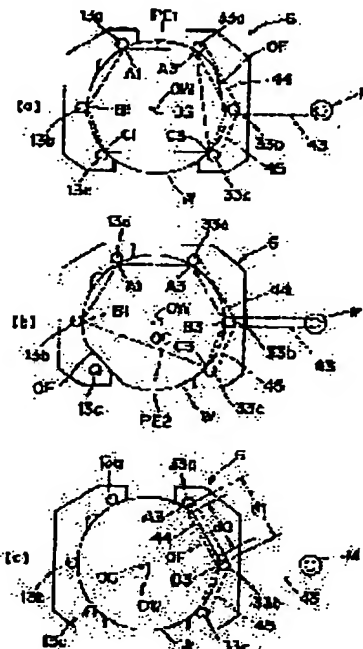
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(54) SUBSTRATE HOLDING DEVICE AND SUBSTRATE TREATING DEVICE UTILIZING SUBSTRATE HOLDING DEVICE

(57)Abstract:

PROBLEM TO BE SOLVED: To provide the substrate holding device, which can hold the substrate even when the approximately circular substrate having the notched part is the object to be treated.

SOLUTION: This wafer holding device has six holding rollers 13a-13c and 33a-33c. Of these rollers, the holding rollers 33a-33c are the driving rollers for imparting turning force to a wafer W, and the holding rollers 13a-13c are the driven rollers, which are rotated by the rotation of the wafer W. These holding rollers 13a-13c and 33a-33c are arranged so that the center of gravity of the wafer W is located in the polygon formed by sequentially connecting the contact points of the holding rollers other than the holding rollers, which are applied on orientation flats OF, and the wafer W when the wafer W having the orientation flats OF is held. Thus, the wafer W can be stably held. Furthermore, an interval d1 between two driving rollers 33a and 33b is set so that the interval is wider than a width d0 of the orientation flat OF. In this way, the wafer W can be stably rotated.



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